

Figure 1. Schematic of the PEALD process and the effect of plasma feed gas H_2 content in controlling the crystallinity of MoS_x films. On the right, Raman spectra of MoS_x films deposited at 150 °C (140 ALD cycles) using different levels of H_2 content are shown.



Figure 2. Effect of H_2 content and deposition temperature on a) crystallinity (colors, analyzed by Raman) and S/Mo ratio (numbers, analyzed by XPS) and b) resistivity (analyzed by four-point probe).



Figure 3. Cross-sectional TEM image showing the layered crystalline structure of a MoS_2 film grown at 100 °C and 80% H₂ content using 50 ALD cycles.